AUTHOR INDEX

Abbati, I. 148
Abeles, F. 324, 325
Abraham, E. 327
Abruna, H.D. 159, 161
Abruna, K.D. 161
Agarwal, M.K. 146, 162
Agranovich V.M. 156, 324, 325, 326, 327
Albery, W.J. 155
Alcock, N.W. 146
Al-Saigh, Z.Y. 167
Ambra, D.M. 161
Anderegg, J.W. 167
Andersen, O.K. 147
Anderson, A.B. 167
Anderson, J. 157
Ansel, G.B. 165
Aomura, K. 167
Aoshima, A. 167
Appelbaum, J.A. 151
Appleby, A.J. 154
Aspnes, D.E. 157, 158
Azzam, R.M.A. 157

Babichenko, V.S. 327
Bachalier, J. 166
Bagdigian, R.M. 166
Baglio, J. 161
Baglio, J.A. 159
Bahl, O.P. 162
Balchin, A.A. 146
Balzarotti, A. 149
Bange, K. 162
Bard, A.J. 153, 155, 159, 160, 161, 165
Bard, D.J. 167
Bardeen, J. 153
Barricelli, L.R. 147
Bärtels, C.C. 166
Bartlett, P.N. 155
Bashara, N.H. 157
Baumann, F.W. 166
Bayliss, S.C. 149
Beal, A.R. 149
Beck, G. 158
Behm, R.J. 157
Bennett, J.C. 159, 165
Benninghoven, A. 156
Berezinskii, V.L. 326
Berger, H. 149
Bernard, L.A. 161
Betts, F. 147
Bewick, A. 157
Bicelli, L.P. 159, 160
Bichsel, R. 149
Bielefeld, R.M. 161
Bither, T.A. 149
Bitterling, K. 159
Bjerkelund, E. 147, 150
Blackmore, J.S. 153
Blank, A.Ya. 326
Bocarsly, A.B. 153
Bockris, J.O'M. 152, 154, 155, 161, 164
Bogge, H. 147
Bonelle, J.P. 167
Bookbinder, D.C. 153
Boramand, F. 161
Born, M. 326
Bouchard, R.J. 149
Bradley, J.S. 164
Bradshaw, A.M. 155, 163
Braicovich, L. 148
Brattas, L. 150
Braun, W. 163
Brec, R. 150
Breysse, M. 166
Brillante, A. 324
Brillson, L.J. 151
Brostigen, G. 147
Bucher, E. 159
Buckley, A. 164
Bullett, D.W. 149, 150
Butler, M.A. 154

Cahan, B.D. 161
Cahen, D. 162
Calabrese, G.S. 159
Calzaferri, G. 161
Campion, A. 157
Candia, R. 166, 167
Canfield, D. 160
Carbone, C. 148
Cardon, F. 153, 155

Cardona, M. 158
Carré, D.J. 163
Carter, G.M. 327
Carver, J.C. 151, 162
Chabal, Y.J. 325
Chan, C.M. 156
Chandra, N. 160
Chang, C.H. 147
Chang, S.S. 166
Chatzitheodorou, G. 151, 161 164, 166
Chen, J.M. 151, 162
Chen, Y.J. 327
Chernyak, V.Ya. 327
Chevrel, R. 147, 165
Chianelli, C.H. 147
Chianelli, R. 162
Chianelli, R.R. 150, 152, 166, 167
Chin, K.K. 152
Chizmadzev, Y.A. 154
Chowdry, U. 158
Clausen, B.S. 166, 167
Clemen, C. 159
Cloud, W.H. 149
Coehoorn, R. 148, 149
Cohen, U. 161
Contractor, A.Q. 161
Conway, B.E. 154
Cornet, D. 166
Cotton, F.A. 152, 165
Cramer, S.P. 147, 150
Cropley, J.B. 164
Crouigneau, P. 158

Daage, M. 167
Damaskin, B. 153
Dare-Edwards, M.P. 155
Daschbach, J.L. 157
Davies, S.M. 151, 162
Davison, S.G. 151
de Beer, V.H.J. 166
de Groot, R.A. 148, 149
Delchar, T.A. 155
del Pennino, U. 148
Demuth, J.E. 157
Deneufville, J.P. 147
Deutscher, S.B. 159
Diemann, E. 147, 166
Dietz, E. 163
Dijkstra, J. 148
Dinardo, N.J. 157
Di Salvo, F.J. 160
Djemal, G. 161
Doering, D.L. 146, 163
Dogonadze, R.R. 154
Doherty, C.J. 160
Dohrmann, J.K. 158
Dominay, R.N. 153
Doni, E. 148
Donohue, P.C. 149
Dose, V. 156
Douay, V. 159
Drube, W. 148
Duben, A.T. 167
Dubovskii, O.A. 326
Duchet, J.C. 166
Dufresne, P. 167
Dujardin, M.M. 325
Duke, C.B. 157
Duncan, T.M. 158
Dwight, K. 161, 165
Dybowski, C. 158

Eastman, D.E. 149
Eberhardt, W. 157
Egdell, R.G. 148
Egert, B. 151, 164
Eguiluz, A. 326
Einstein, T.L. 156
Ekardt, W. 152
Elconin, M.K. 147
Eltzner, W. 166
Enemark, J.H. 147
Ennaoui, A. 147, 149, 164
Ertl, G. 151, 155
Etman, M. 159, 160
Evans, B.L. 149
Evans, E.L. 162
Ezzaouia, H. 163, 164

Fan, F.F. 160
Fan, F.R. 153, 159
Farneth, W.E. 158
Faulkner, L.R. 153
Fauster, Th. 156
Feinberg, E.L. 324
Felsen, L.B. 326
Feng, H.C. 151, 162
Fermor, J.H. 150
Feshbach, H. 326
Feuerbach, B. 155
Fiechter, S. 147, 149, 151, 161, 164
Firsov, E.I. 325
Fitton, B. 155
Flack, H.D. 147
Fleischauer, P.D. 151
Fleischauer, P.J. 163
Fleischmann, A. 158
Flipse, C.J.F. 148
Fock, V.A. 324
Foley, J.K. 157
Folkerts, W. 149

Fong, C.Y. 148, 150
Fornarini, L. 160, 161
Foulias, S.D. 151
Francis, S.D. 160
Frankl, D.R. 152
Fraser, D. 167
Freedhoff, H. 326
Freeman, A.J. 150
Freeouf, J.L. 149
Frese, K.W. 155
Freund, T. 158
Friend, R.H. 148
Friend, R.K. 153
Frumkin, A. 153
Fuchs, R. 326
Fujimori, A. 150, 165
Fujishima, A. 154
Furimsky, E. 166
Furnseth, S. 147
Furtak, T.E. 160

Gapotchenko, N.I. 326
Gard, P. 150
Gärtner, W.W. 154
Gengembre, L. 167
Gerischer, H. 151, 153, 154, 158, 159, 160, 161, 167
Gibbs, H.M. 327
Ginley, D.S. 161
Ginzburg, V.L. 324
Girlanda, R. 148
Glass, N.E. 326
Gliemann, G. 152
Gobrecht, J. 161
Gocke, E. 165
Goldstein, Y. 151
Gomer, R. 153
Gomes, W.P. 153, 155, 158
Goodenough, J.B. 146, 147, 148, 149
Göpel, W. 150
Gordon, J.G. III 324
Gorochov, O. 159, 164
Goshi, Y. 149
Goslowski, H. 161, 164
Gottesfeld, S. 159
Grant, J.T. 156
Grasso, V. 149
Grimblot, J. 167
Grimmeiss, H.G. 147
Grondev, S.N. 165
Grover, N.B. 151
Gurney, R.W. 154
Gutierrez, C. 153
Gutmann, A. 157
Guy, P.J. 166

Haas, C. 148, 149
Hahn, H. 147
Hall, R.N. 155
Hall, W.K. 167
Hamakawa, Y. 158
Hamann, D.R. 151
Hamnett, A. 148, 155
Haneman, D. 158
Hansen, W.N. 153, 161
Haraldsen, H. 150
Harris, F.E. 149
Harris, S. 149, 152, 167
Harrison, D.J. 159, 161
Haycock, D.E. 149
Hayes, R.A. 166
Heiland, G. 150
Heiland, W. 156
Heindl, R. 163
Heitbaum, J. 167
Heller, A. 160
Hemmel, R. 149
Henglein, A. 166
Henzler, M. 157
Herm, D. 164
Herman, F. 148, 151
Hibma, T. 146
Higginbotham, I.G. 162
Hillebrecht, F.U. 149
Himpsel, F.J. 148, 151
Hiraki, A. 152
Hirami, K. 149
Hirschwald, W. 150
Hodgson, K.O. 150
Hoffman, R. 148
Hoffman, R.W. 158
Hoffmann, F.M. 157
Hoffmann, R. 150, 151
Hoffmann, W.K. 146, 161
Hollins, P. 157
Holtier, F. 157
Holzwarth, N.A.W. 149
Honda, K. 154
Hönle, W. 147, 150, 165
Hope, G.A. 159
Hösler, W. 157
Hubbard, A.T. 161, 162
Huggins, R.H. 150
Hughbanks, T. 150
Hughes, G.J. 152, 163
Hughes, H.P. 149, 163
Hughes, S.J. 162
Hulliger, F. 149
Hullinger, F. 146

Ibach, H. 156
Ihara, H. 150
Imbihl, R. 157

Ingledew, J.W. 166
Ireland, P.J. 162

Jacobi, K. 157
Jacobsen, A.C. 166
Jacobson, A.J. 147, 150
Jaeger, C.D. 159
Jaegermann, W. 146, 147, 149, 150, 151, 158, 159, 160, 161, 162, 163, 164, 165
Janata, E. 159, 160
Jani, A.R. 146
Jarlborg, I. 150
Jarlborg, T. 150
Jeiva, M. Rodriguez 166
Jellinek, F. 146, 147, 150
Jellinek, F.B. 150
Jerome, D. 153
Johnson, K.H. 149
Jones, D. 326
Jones, R.O. 151
Jostes, R. 147, 148, 165

Kadjik, F. 150
Kam, K. 160, 161
Kam, K.K. 160
Kamaratos, M. 163
Kamieniecki, E. 159
Kapert, D.L. 164
Kaplan, A.E. 327
Kaplan, R. 146
Karavaiko, G.I. 165
Kashiwakura, J. 149
Katz, L. 165
Kautek, W. 152, 159, 160, 161
Kazmerski, L.L. 162
Kelly, J.J. 155
Kemeny, P.C. 148
Kendelewicz 152
Kennou, S. 151, 163
Kerchove, F. v.d. 155
Kershaw, R. 159, 161, 165
Khan, A. 152
Khan, S.U.M. 152, 154, 155
Kharkats, Y.I. 154
Khekshus, A. 150
Kimura, K. 150
Kirkpatrick, C.G. 158
Kita, H. 152, 158
Kjekshus, A. 146, 147, 150
Kliewer, K.L. 326
Klimova, L.G. 327
Kline, G. 160, 160
Klose, W. 147
Kolb, D.M. 153, 157, 158, 161
Koma, A. 151, 161, 163
Könenkamp, R. 148, 151
Konigs, A.J.A. 166
Kordesch, M.E. 158
Korzeniewski, C. 157
Kötz, E.R. 161
Kötz, R. 157, 161, 162
Kou, W.W. 149
Krause, M.J. 164
Kravtsov, V.E. 324, 325, 326
Krönert, W. 147
Kruger, J.H. 157
Kubiak, C.P. 159, 163
Kuhlenbeck, H. 164
Kühne, H.-M. 149, 150, 161, 163
Kunst, M. 151, 158, 161, 164
Kurmaev, E.Z. 150
Kurtin, A. 151
Kutzenov, A.M. 154
Kuznetsoc, A.M. 154

Lachish, U. 161
Lacroix, M. 151, 166
Ladas, S. 163
Laine, R.M. 164
Lamy, C. 158
Landa, S. 166
Landau, L.D. 326
Lander, J.J. 152
Landsberg, P.T. 153
Laser, D. 155
Lauer, S. 149
Leamy, H.J. 160
Lee, S.W. 326
Leland, J.K. 160, 165
Lemasson, P. 154
Leontovich, M.A. 325
Leskova, T.A. 324, 326
Levich, V.G. 154
Levine, J.C. 151
Levy, F. 149
Levy-Clement, C. 165
Lewerenz, H.J. 146, 160, 161
Lewis, N.S. 153
Ley, L. 148
Li, E.K. 149
Li, J. 155
Li, X.P. 164
Liang, K.S. 147, 149, 152, 162
Liang, W.S. 149
Liang, W.Y. 146, 148, 149
Lieth, R.M.D. 146
Lifshitz, E.M. 326
Lilie, H.J. 146
Lilie, J. 162
Lin, C.L. 166
Lince, J.R. 151, 163

Lindau, I. 148, 152
Lipsch, J.M.T.G. 166
Liu, C. 164
Lohmann, F. 153
Lopez-Rios, T. 324, 325
Lotz, W. 148
Lowson, R.T. 165
Lübke, M. 153, 160
Luck, J. 161, 164
Lugato, L. 327
Lundgren, D. 165
Lüth, H. 150, 156

Maas, C. 148
MacDonald, D.D. 158
Madey, T.E. 156, 157, 162
Mai, J. 147
Mal'shukov, A.G. 324, 325
Many, A. 151
Maradudin, A.A. 156, 326, 327
Marcus, R.A. 154
Marcuvitz, N. 326
Margaritondo, G. 148
Marseglia, E.A. 150
Martensson, N. 150
Marzik, J.V. 165
Materlik, G. 158
Maternova, J. 167
Mattheiss, L.F. 150
McCarty, K.F. 166, 167
McEvoy, A.J. 159, 160, 161
McGill, T.C. 151
McGilp, J.F. 163
McGovern, I.T. 148, 151, 162, 163
McIntyre, R. 159, 161
McKinley, A. 163
McMenanmin, J.C. 148
Mead, C.A. 151
Meixner, J. 326
Memming, R. 152, 154, 155, 159, 160
Menezes, S. 160
Mgoduka, N. 164
Miller, B. 160
Miller, J.D. 166
Mills, D.L. 156
Miremadi, B.K. 162
Mittra, R. 326
Möbius, D. 324
Monceau, P. 153
Mönch, W. 151, 157
Mondio, G. 149
Morrison, S.R. 151, 152, 162
Morse, P.M. 326
Morup, S. 166
Moskaleva, M.A. 325
Mott, N.F. 153
Moyes, R.B. 167
Mramatsu, S. 149
Mrstik, B.J. 146
Muetterties. E.L. 164
Müller, A. 147, 165, 166
Müller, K. 162
Müller, N. 161
Myamlin, V.A. 152
Myerson, A.S. 166

Nagasubramanina, G. 159, 160
Naish, C.C. 148
Nakabayasji, S. 154
Nakai, S. 149
Nazin, V.G. 325
Neff, H. 161, 162
Ness, P 147
Newman, N. 152
Nidda, A. 167
Nishmo, T. 158
Nogami, J. 148
Nohl, H. 147
Noonan, J.R. 158
Norman, D.S. 163
Nyholm, R. 150

Ogawa, S. 149
Ohno, Y. 149
Ohuchi, F. 158
Ohuchi, F.S. 146, 162, 163
Okada, S. 149
Oliver, A. 158
Oshawa, A. 149
Otto, A. 157
Ouvard, G. 150
Overmeire, F. v. 155

Pan, W.H. 150
Panzer, G. 164
Panzner, G. 151
Papageorgopoulos, C.A. 151, 163
Paranthanam, M. 165
Parke, A.W. 148
Parkinson, B.A. 146, 160, 161, 162, 167
Parsons, R. 163
Passler, M.A. 157
Patel, J.W. 162
Patel, N.G. 162
Path, D.L. 161
Peat, R. 155, 159
Pecoraro, T.A. 166, 167
Pekar, S.I. 324
Pendry, J.B. 156
Peraldo-Bicelli, L. 161

Perone, S.P. 159
Perrin, C. 165
Perrin, A. 147, 165
Peter, L.M. 154, 155, 159,
Pettenkofer, C. 146, 147, 162 163, 164, 165
Peyghambarian, N. 327
Philpott, M.R. 324, 326
Piacentini, M. 149
Piazza, S. 163
Pisharody, K.P.R. 146
Plieth, K. 147
Plummer, E. 157
Pockrand, I. 324
Pollak, R.A. 150
Pollmann, J. 151
Pons, S. 157
Potel, M. 165
Poulios, I. 164
Price, D.M. 166
Prins, R. 166
Pritchard, J. 157

Rabenau, A. 147
Rabloff, G.W. 157
Rach, E. 167
Radlik, W. 163
Raether, H. 156
Rajeshwar, K. 155
Ralston, J. 166
Ramaker, D.E. 156
Ramasesha, S.K. 146
Rao, C.N.R. 146
Rashid, M.H. 150
Razzini, G. 160, 161
Read, W.T., Jr. 155
Reddy, A.K.N. 154
Redon, A.M. 163
Reichmann, J. 155
Reidel, D. 166
Reimer, L. 157
Reinicke, T.L. 146
Reiss, H. 152
Reskov, Y.V. 152
Ricco, A.J. 159, 161
Richardson, J.H. 159
Richtering, W. 161
Rijnsdorp, J. 147
Rob, D. 160
Robbins, A.J. 153
Roberts, J.L., Jr. 158
Robinson, J. 158
Rosasco, S.D. 162
Rose, A. 153
Rosenthal, J. 159
Ross, P.M. 161
Rost, E. 150
Rotermund, H.H. 163
Roxlo, C.B. 167
Ruppert, A.F. 167

Sakata, T. 159, 160
Salmeron, M. 162
Salvador, P. 153, 155
Sander, U. 158
Sarid, D. 327
Sass, J.K. 158, 162
Sato, K. 149
Sawatzky, G.A. 148, 149
Sawyer, D.T. 158
Sayers, C.M. 167
Schäfer, H.L. 152
Schardt, B.D. 162
Scheffler, K. 155
Scherson, D. 152
Scherson, D.A. 153, 158, 161
Schindler, K.M. 158
Schira, R. 167
Schlegel, A. 149
Schlesinger, Z. 325
Schlüter, M. 148, 151
Schmäh, M. 158
Schmeiber, D. 146, 158, 160, 162
Schneemeyer, L.F. 159, 160, 161, 163
Schollhorn, R. 150
Scholz, G.A. 159
Schottky, W. 152
Schrader, G.L. 166, 167
Schubert, B. 159, 164, 165
Schuit, G.C.A. 166
Schumacher, R. 158
Scott, R.A. 150
Scrosati, B. 160, 161
Sculfort, J.L. 154
Seehra, M.S. 149
Seki M.149
Sekita, M. 150, 165
Sellmyer, D.J. 150
Sen, R.S. 154
Sergent, M. 147, 165
Shafer, M.W. 150
Shen, T.P. 326
Shepherd, F.R. 151
Shibuya, S. 149
Shkerdin, G.N. 327
Shockley, W. 151, 153, 155
Shomina, E.V. 325
Siemons, W.J. 149
Sievers, A.J. 325
Silbernagel, B.G. 166
Silver, M. 165
Silvestre, J. 151

Simon, R.A. 161
Siripala, W. 155
Skibowski, M.J. 148
Skillman, S. 148
Skin, S. 149
Sleight, A.W. 158
Smith, R.W. 166
Smith, S.D. 327
Solomun, T. 161, 162
Somerfeld, A. 326
Somorjai, G.A. 162
Sourisseau, C. 150
Spahni, W. 161
Sparrow, G. 161
Spicer, W.E. 148, 151, 152
Spiesser, M. 164
Srivastava, V.K. 324
Staley, R.H. 158
Starnberg, H.I. 163
Steffensen, A. 150
Stegeman, G.I. 326, 327
Stehblow, H.H. 158
Stickney, J.L. 162
Stiefel, E.I. 150
Stiles, P.J. 157
Stirpe, F. 160
Stockbauer, R. 156
Stöckel, W. 158
Stöhr, J. 156
Straub, D. 148
Streetman, B.G. 158
Suga, S. 149
Sugioka, M. 167
Sugiura, C. 149
Sutin, N. 154
Suzuki, I. 149
Swalen, J.D. 324
Szacki, W. 147
Sze, S.M. 154
Szklaczyk, M. 161
Szklarczyk, M. 161

Taglauer, E. 156
Tamm, J.E. 151
Taniguchi, M. 149
Taube, H. 154
Tauster, S.J. 162, 166
Telliette, M.J. 166
Tenne, R. 161
Terhell, J.C.J.M. 146
Theeten, J.B. 157
Theye, M.L. 325
Thiel, F.A. 162
Thomas, J.M. 162
Thompson, W.J. 157
Tomkiewicz, M. 155
Tomlinson, W.J. 327
Topsøe, H. 166, 167
Topsøe, N.Y. 167
Trahar, W.J. 166
Trasatti, S. 153
Trautwein, A.X. 149
Triboulet, R. 154
Tributsch, H. 146, 149, 150, 151, 155, 158, 159, 160, 162, 163, 164, 165, 166
Tryson, G. 153
Turner, J.A. 160

Uelhoff, W. 158
Ulstrup, J. 154
Uosaki, K. 152, 158
Urch, D.S. 149

Vainstein, L.A. 324
Valentine, J. 167
Valster, A. 166
van Brüggen, C.F. 149
van der Heide, H. 149
van Henzen, A.A. 148
van Hove, M.A. 146, 147, 156
Van Kranendonk, J. 326
Vanmaekelbergh, D. 153, 155
Vante, N. Alonso 150, 164, 165
Vasbi, M.N. 146
Vaska, L. 167
Vijh, A.K. 158
Vinogradov, E.A. 324, 325
Voronko, A.I. 327
Vrinat, M. 166
Vuye, G. 324, 325

Wachter, P. 149
Wada, H. 165
Wada, K. 150
Wadsworth, M.E. 165
Wagner, F.T. 161
Wahlunng, G. 324
Walker, W. 164
Wallis, R.F. 326
Walton, E.G. 153
Watanabe, H. 149
Webb, B.C. 325
Weinberg, W.H. 156
Weisser, J. 166
Wells, A.F. 146
Wells, P.D. 167
Wentrcek, P.R. 167
Wetzel, H. 164
Wheeler, B.L. 159, 160, 165
Whitaker, M.A.B. 162
White, H.S. 160, 161
White, M.S. 159

Wiech, G. 149
Wildervanck, J.C. 146
Wilkinson, R. 152
Wille, R. 161
Williams, F. 151
Williams, P.M. 148
Williams, R.H. 148, 162, 163
Williams, R.M. 148, 151
Willig, F. 159, 160
Willsau, J. 167
Wilson, J. 153
Wilson, J.A. 146, 150
Wilson, R.H. 155
Wise, H. 167
Wisel, C. 166
Wohlfahrt-Mehrens, M.S. 167
Wold, A. 148, 159, 161, 162, 165
Wolf, E. 326
Woodruff, D.P. 155
Woods, R. 164
Wright, C.J. 167
Wrighton, M.S. 153, 159, 160, 161, 163
Wyckoff, R.W.G. 146
Yaeger, E. 161
Yakovlev, V.A. 325
Yamaguchi, T. 149
Yamamato, K. 157
Yamamoto, H. 149
Yamashenki, Y.M. 150
Yao, S.B. 158
Yates, J.T. 157
Yeager, E.R. 158
Yodson, V.I. 324
Yoffe, A.D. 146, 148
Yong, S.Y. 146, 147
Yoshimura, K. 151, 163
Young, V.Y. 161
Yudson, V.I. 325, 326
Yun, L.S. 153
Yvon, K. 147, 150

Zegenhagen, J. 158
Zhizhin, G.N. 324, 325, 326
Ziemer, J. 159
Zoski, G.D. 159
Zoski, G.J. 159
Zwicker, G. 157

SUBJECT INDEX

Adsorption experiments, semiconductor/electrolyte interface simulation and 92-97
Ag layers on Al, surface polariton dispersion and and 183-186

Bulk plane waves, diffracted wave fields and 218-225
Bulk radiation
  by surface polaritons 209-210
  surface polariton conversion into 233-236, 251-255

Catalysis, chalcogenides and 123, 135-138
Chalgogenides
  in catalysis 135-138
  electronic structure of 19-23
    chevrel-type phases 30-31
    layered semicoductors 24-27
    one-dimensional semiconductors 31-32
    pyrite-type semiconductors 27-29
  structure types of
    chevrel-type 15-17
    layered 6-12
    one-dimensional 17-19
    pyrite-type 12-14
Charge carriers
  at surfaces 50-52
  interfacial dynamics of 54-57
  light excitation of 70-71
  trapping and detrapping of 50-52
Charge transfer processes 52-54
Chevrel-type phases
  electronic structure of 30-31
  intercalation of 33
(Chevrel-type, cont.)
  structure of 15-17
Cluster compounds
  (photo)electrochemical studies of 120-123
  interfacial processes of 117-124
Conversion coefficients
  surface polariton to bulk radiation and 251-255
Conversion efficiency
  surface polariton into bulk radiation
    incident to impedance step 233-236
Cyclic voltammetry, 74-75

Dichalcogenide structures
  chevrel-type 15-17
  layered 6-12
  one-dimensional 17-19
  pyrite-type 12-14, 15
Diffraction
  of electromagnetic waves, surface and bulk 199-229
    experimental observation of 194-199
    general characteristics of 174-178
    nonlinear 301-313
    by semi-infinite film with spatial dispersion 256-267
Diffraction problem
  numerical solution of 308-311
Dispersion
  curve splitting in infrared region and 187-190
  of surface polariton 178-183

Edge condition, wave incidence onto step and 204-207
Edge modes, effect of, 270-277

Effective boundary condition
normal incidence onto step and 199
oblique incidence of surface polaritons and 242-243
surface polariton diffraction and 256-260
Electric techniques, in surface characterization 66-71
Kelvin probe 69
light excitation charge carriers 70-71
microwave conductivity measurement 70-71
van der Pauw contact method 70
Electrochemical techniques
cyclic voltammetry 73-75
experimental setup for 72-73
impedance measurements in 73-75
laser pulse photoresponse measurements 77
step perturbation 75-76
Electromagetic waves
diffraction of 199-277
normal incidence of, onto step 199-229
oblique incidence of
onto interferometer boundary 296-301
onto semi-infinite film 256-267
surface polariton and 242-255
transformation of, by impedance step 229-242
Electronic structure
Coulomb potentials of atomic orbitals and 20-23
electron interaction contribution to 22-23
of layered semiconductors 24-27
LCAO approach to 19-20
Energy transformation coefficients 230-232, 238
of reflection and transmission 265-267
surface polariton dispersion and 263-264
Excitation
by surface polaritons 210-218
by bulk polaritons 218-225

Fabry-Perot interferometer
normal incidence onto film edge and 277-296
oblique incidence onto boundary and 296-302
Fields
diffracted, by surface polaritons 210-218 210-218
wave, bulk waves and 218-225
Frequency dependence
conversion of incident surface polariton into bulk radiation and 236-238

Hydrometallurgy, metal sulfide interfaces and 126-128

Impedance approximation
in diffraction of surface and bulk electromagnetic waves 225-229
Impedance measurements, 73-75
Impedance step
wave transformation by 229-242
conversion efficiency and, surface polariton into bulk radiation 233-236
resonance effects and 236-239
specular reflection anomalies and 239-242
time-averaged power flow of surface wave and 229-230
transformation coefficients and 230-232
surface polariton from clean metal surface and 203-204
Incidence
Fabry-Perot interferometer and 277-301
normal
onto film edge 277-296
onto step 199-229
oblique, onto interferometer boundary 296-301
onto impedance step 203-204
diffracted fields and, excited 210-225
edge condition and 204-207
from film-coated metal surface 208-209

(Incidence, cont.)
impedance approximation and 225-229
onto step
effective boundary conditions and 199-201
general equation for 201-203
Intercalation
of layered compounds 104-106
of semiconductor/metal interface 105-106
of transition metal compounds 32-33
Interfacial chemistry
hydrometallurgy and 126-128
pollution control and 133-135
Interfacial coordination chemistry 138-144
Interfacial problems, at sulfide interfaces 126-135
Interfacial processes
in cluster compounds 117-118
characterisation problems and 124
in material research 119-120
multielectron transfer catalysis and 123
photoelectrochemical studies of 120-123
in layered compounds
at electrolyte interfaces 88-99
photochemical properties of 78-88
of semiconductor/metals 99-106
in pyrite compounds
interfacial coordination photoelectrochemistry of 110-111
photoelectrochemical properties of 106-109
surface studies of 111-117

Kelvin probe 69
Kinetics
of charge carriers
interfacial 54-57
at surfaces 50-52
of charge transfer processes 52-54

Laser pulse photoresponse measurements 77
Layered compounds
intercalation of 104-106
interfacial processes of 78-88
Layered dichalcogenide structures 6-12
Layered semiconductors
electronic structure of 24-27
intercalation of 33
interfacial processes of 78-88
properties of 25-26
surface spectroscopy characterization of 88-99
surface structure of 6-12
Light excitation charge carriers, in surface characterization 70-71

Metal sulfide interfaces, mineral bio-geochemistry and 124-126
Microoganisms, metal sulfide interface leaching by 128-133
Microwave conductivity measurement, in surface characterization 70-71

One-dimensional semiconductors
electronic structure of 31-32
surface structure of 17-19
Optical techniques, in surface characterization 66, 67
Oxidation reactions
in layered structures 89-90, 91
SEM microprobe analysis and 91
XPS and 90-91
Perturbation, step, in semiconductor electrochemistry 75-76
Pollution control, interfacial chemistry of sulfide interfaces and 133-135
Pyrite compounds
electronic structure of 27-29

(Pyrite compounds, cont.)
interfacial processes of 110-111
(photo)electrochemical properties of 106-109
properties of 29
structure of 12-14, 15
surface studies of 111
LEED 116
SXPS 116-117
XPS 112-115

Reactivity
of pyrite compound surfaces 112-117
of semiconductor/electrolyte interfaces 89-97
of semiconductor/metal interfaces 99-106
Reflection and transmission coefficients, surface polariton diffraction and 265-267
Resonance effects, incident to impedance step 236-239
Resonance region, surface polariton dispersion in 173-178

S120 dye on silver
surface polariton dispersion and 178-183
Semiconductor/adsorbate interfaces
extrinsic surface states and 39-40
surface charge layers and 40-43
thermodynamics of 39-43
Semiconductor/electrolyte interfaces
Fermi level pinning and 47-49
(photo)electrochemical techniques and 78-88
Schottky barrier model and, idealized 43-47
simulation of
H^2O absorption and 92-93
halogen absorption and 95-99
surface spectroscopy characterization of 88-99
thermodynamics of 43-49
Semiconductor interfaces
kinetics of 49-57
surface characterization techniques and 57-60
electric 66-71
in-situ 67
optical 66, 67
UHV 60-66
thermodynamics of 34-39
Semiconductor/metal interfaces
thermodynamics of, intercalation reactions and 104-107
Semiconductors, electrochemical techniques in 72-77
Semi-infinite film, with spatial dispersion, surface polariton diffration by 256-277
Specular reflection, of bulk waves 239-242
Sulfide interfaces
chemistry of and pollution control 133-135
hydrometallurgy interfacial problems and 126-128
leaching microorganisms and 128-133
in natural environments 124-126
Surface characterization
electric techniques of 66-71
of layered semiconductors 88-99
optical techniques of 66, 67
of pyrite compounds 112-117
spectroscopic methods for 60-66
Surface polariton dispersion
diffraction characteristics and 174-178
investigations of 178-198
additional surface polaritons and 190-194
Ag layers on Al and 183-186
curve splitting in infrared region 187-190
S120 dye on silver and 178-183
in resonance region 173-178
Surface polaritons
diffraction of 174-178, 194-199, 199-276, 301-313

(Surface polaritons, cont.)
dispersion of 173-199
Fabry-Perot type interferometer for 277-301
incidence of, from film-coated surface 208-209
incident to impedance step conversion efficiency into bulk radiation 233-236
nonlinear diffraction of 301-313
oblique incidence of 242-255
conversison coefficients, surface polariton to bulk radiation 251-255
effective boundary condition and 242-243
incidence onto impedance step and 244-246
transmission and reflection coefficients and 249-251

surface electromagnetic waves and 296-298
tranformation coefficients and 230-232
Surface spectroscopies
pyrite compounds and
LEED 116
SXPS 116-117
XPS 112-115
in semiconductor/electrolyte interfaces 98-99
characterization of 88-89
reacted characterization and 89-91, 97
simulation and 92-97
in semiconductor interfaces 60-66, 67
in semiconductor/metal reactivity 99-106
LEED and 102-103
SXPS and 103
XPS and 103
Surface wave guide modes 298-301

Thermodynamics
of clean semiconductors
electronic structure of 36-38
preparation of 34-36
of semiconductor/adsorbate interfaces

(Thermodynamics, cont.
extrinsic surface states of 39-40
surface charge layers of 40-43
of semiconductor/electrolyte interfaces
Fermi level pinning and 47-49
idealized Schottky barrier model 43-47
of semiconductor/metal intercalation reactions 104-107
Time-averaged power flow of surface wave 229-230
Transformation coefficients
edge mode effect on 270-277
incident to impedance step 230-232, 238
surface polariton diffraction and 267-269
Transmission and reflection coefficients, oblique 249-251
Transmission coefficients
interference phenomena and 287-290
onto interferometer boundary 290-296
for surface polaritons 285-296

Ultra-high vaccum (UHV) techniques
in electrolyte interface characterization 88-99
adsorption experiements and 92-97
oxidation reactions and 89-91
semiconductor/electrolyte junction simulation in 92-97
of semiconductor/metal reactivity 99-106
LEED and 102-103
SXPS and 103
XPS and 103
XP- spectra and 101-102
in surface characterization 60-66
LEED 63-64, 116
LEISS 64-66
UPS 60-63
SXPS 116-117
XPS 60-63, 112-115

van der Pauw method, 70
Vibrations, transition layer, and surface polariton dispersion 173-199

Wave transformation
by impedance step 229-242
conversion efficiency and 233-236
resonance effects of 236-239
(Wave transform., cont.)
specular reflection anomalies of 239-242
time-averaged power flow and 229-230
transformation coefficients and 230-232
Waves, surface electromagnetic oblique incidence of 296-301